



THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of : **Confirmation No. 9191**
Makoto AKIZUKI et al. : Docket No. 2001-1897
Serial No. 10/025,899 : Group Art Unit 1762
Filed December 26, 2001 : Examiner Bernard D. Pianalto

METHOD FOR FORMING GAS CLUSTER AND
METHOD FOR FORMING THIN FILM

RECEIVED
AUG 29 2003
TC 1700

PETITION FOR EXTENSION OF TIME

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Petition hereby is made for a three month extension of time to respond to the communication of
February 27, 2003.


The fee of \$930.00 is

- (X) submitted herewith.
() to be charged to Deposit Account No. 23-0975. A duplicate copy of this Petition is enclosed.

() Small entity status of this application is established by a Small Entity Status Assertion which
() is enclosed.
() has been previously submitted.

Respectfully submitted,

Makoto AKIZUKI et al.

By 
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August 27, 2003